

Special Topics on Basic EECS I Design Technology Co-Optimization

Lecture 2

Sung-Min Hong (smhong@gist.ac.kr)

Semiconductor Device Simulation Laboratory

Department of Electrical Engineering and Computer Science

Gwangju Institute of Science and Technology (GIST)

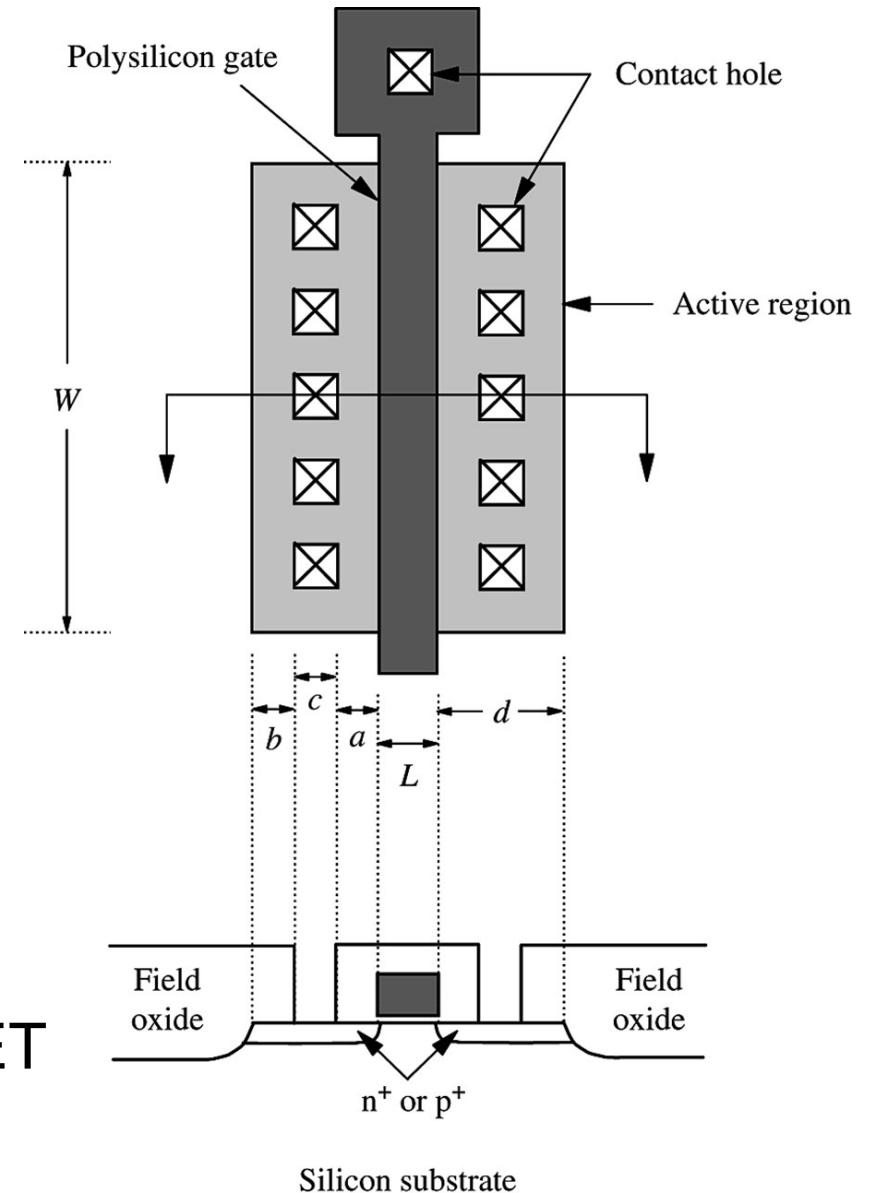
L2

Traditional MOSFET scaling

- Ground rules
 - Length: L
 - Width: W
 - Width of n^+ or p^+ diffusion: d
- Scaled by the same factor, κ (> 1)
 - Its typical value is $\kappa \approx 1.4$. ($\kappa^2 \approx 2$)
 - Area: $\times \frac{1}{\kappa^2}$
 - Oxide capacitance (per area): $\times \kappa$

Layout and cross-section of a MOSFET
(Prof. Taur's book)

GIST Lecture



Constant-field scaling

- Discussion

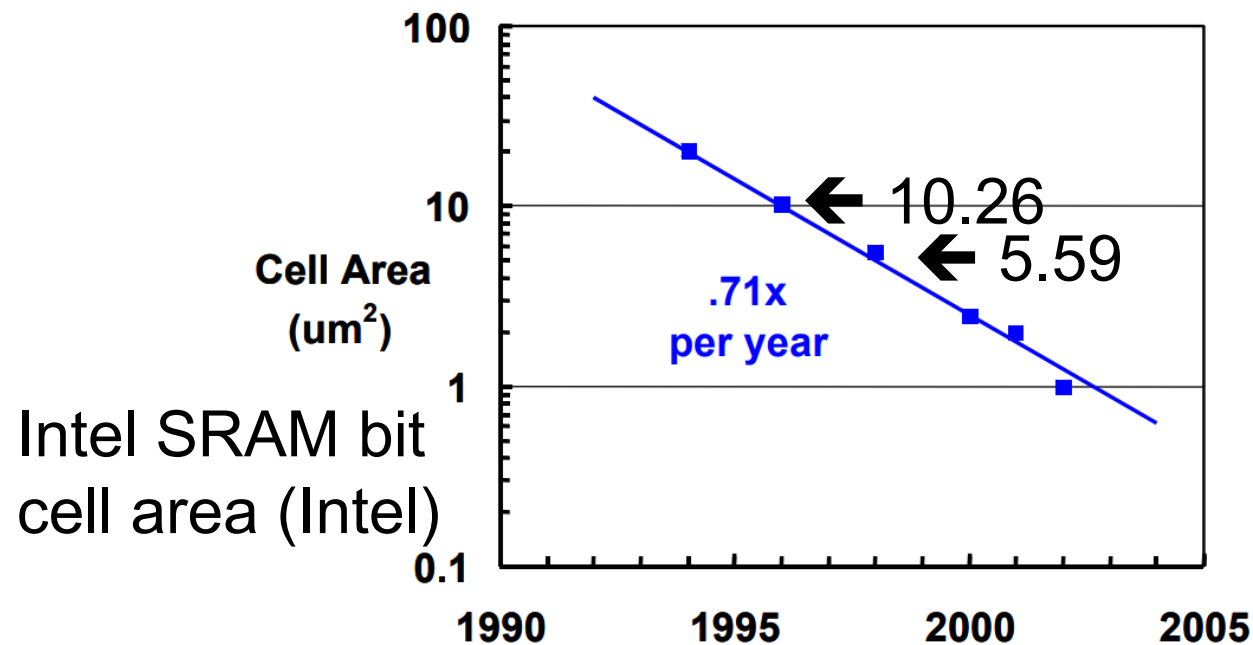
- Gate capacitance follows $C_{ox}WL$, $\times \frac{1}{\kappa}$.
- Recall that the saturation current follows $\mu C_{ox} \frac{W}{L} (V_{DD} - V_t)^2$.
- When V_{DD} becomes $\times \frac{1}{\kappa}$, the saturation current also becomes $\times \frac{1}{\kappa}$. ($\times 0.7$ low current)
- Charge stored (gate capacitance $\times V_{DD}$) scales $\times \frac{1}{\kappa^2}$.
- The delay (\sim performance) becomes $\times \frac{1}{\kappa}$.
- At an increased frequency ($\times \kappa$), power becomes $\times \frac{1}{\kappa^2}$.

Ideal case with $\kappa = 1.4$

- Generation-to-generation improvement

0.5X Area & +40% Speed & -50% Energy

- From today's view, improvement seems to be tremendous.
- Let's see an example, 0.25 μm (Intel Pentium II and III, 1997)
→ 0.18 μm (Intel Pentium 4, 1999)



Intel 0.25 μm @ IEDM 1996

- Fact sheet

- $V_{DD} = 1.8$ V. Actual channel length is $0.18 \mu\text{m}$. Oxide thickness is 4.5 nm. Saturation currents are $0.70 \text{ mA}/\mu\text{m}$ (N-ch) and $0.32 \text{ mA}/\mu\text{m}$ (P-ch). Subthreshold slope is less than $85 \text{ mV}/\text{dec}$. N-ch/P-ch threshold voltage are $0.28/-0.27$ V. DIBL values are $65/63 \text{ mV}/\text{V}$.

- Transistor's $\frac{CV}{I}$:

- $\sim 3.5 \text{ psec}$ (N-ch)

- $\sim 7 \text{ psec}$ (P-ch)

- Then, inverter delay?*

- SRAM: $10.26 \mu\text{m}^2$

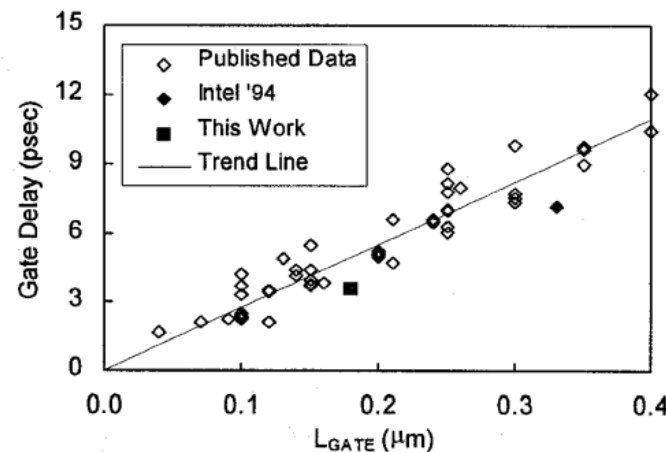


Fig. 9 N-ch CV/I gate delay vs. gate length trend

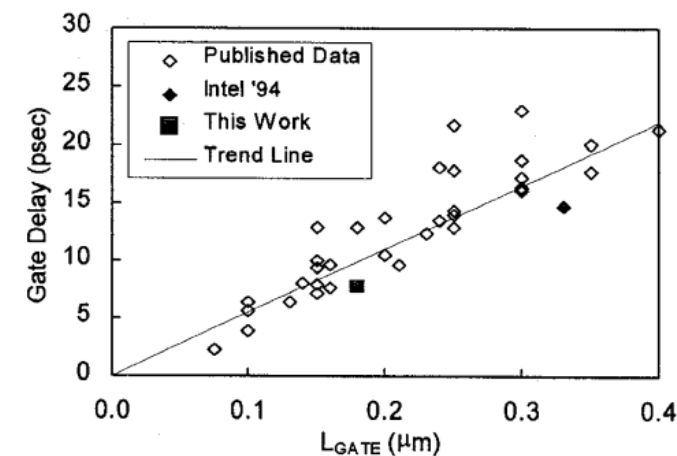


Fig. 10 P-ch CV/I gate delay vs. gate length trend

Intel 0.18 μm @ IEDM 1998

- Fact sheet (Red ones for 0.18 μm)
 - $V_{DD} = 1.3 - 1.5 \text{ V}$ (1.8 V). Actual channel length is 0.13 μm (N-ch)/0.15 μm (P-ch) (0.18 μm). Oxide thickness is 3.0 nm (4.5 nm). Saturation currents at 1.5 V are 0.94 mA/ μm (0.70 mA/ μm) (N-ch) and 0.42 mA/ μm (0.32 mA/ μm) (P-ch). Subthreshold slope is less than 90 mV/dec (85 mV/dec). N-ch/P-ch threshold voltage are 0.30/-0.24 V (0.28/-0.27 V).
 - DIBL?
 - Inverter delay (fan out = 1):
<11 psec at 1.5 V
 - SRAM: 5.59 μm^2 (10.26 μm^2)

Inverter
gate delay
(Intel)

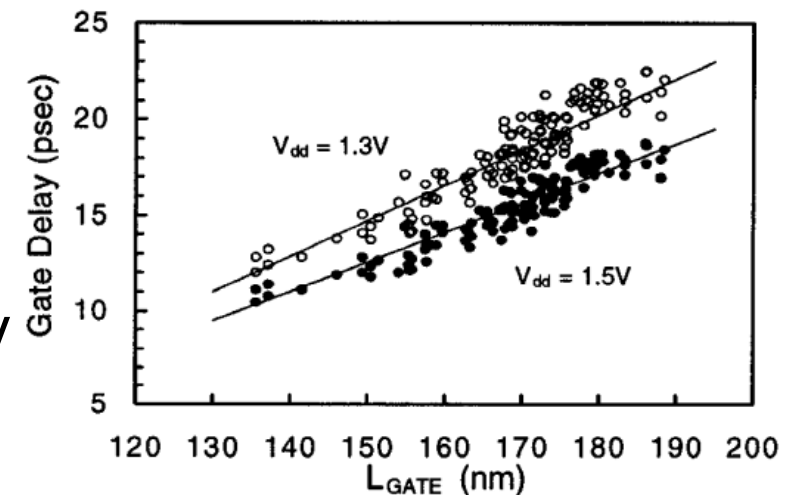
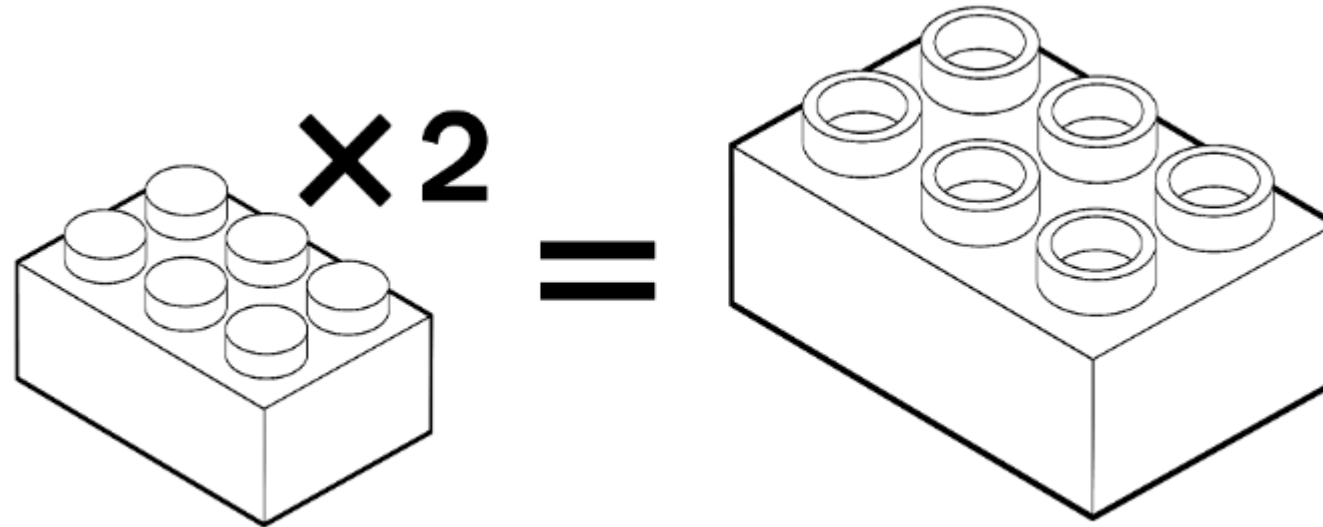


Fig. 10 Inverter gate delay per stage vs. L_{GATE} , FO=1

When you read those papers,

- You can find that:
 - The authors mainly discuss the single device performance.



Lego brick and Duplo brick (Lego)

Chronicles

- Intel and TSMC. IEDM and VLSI papers

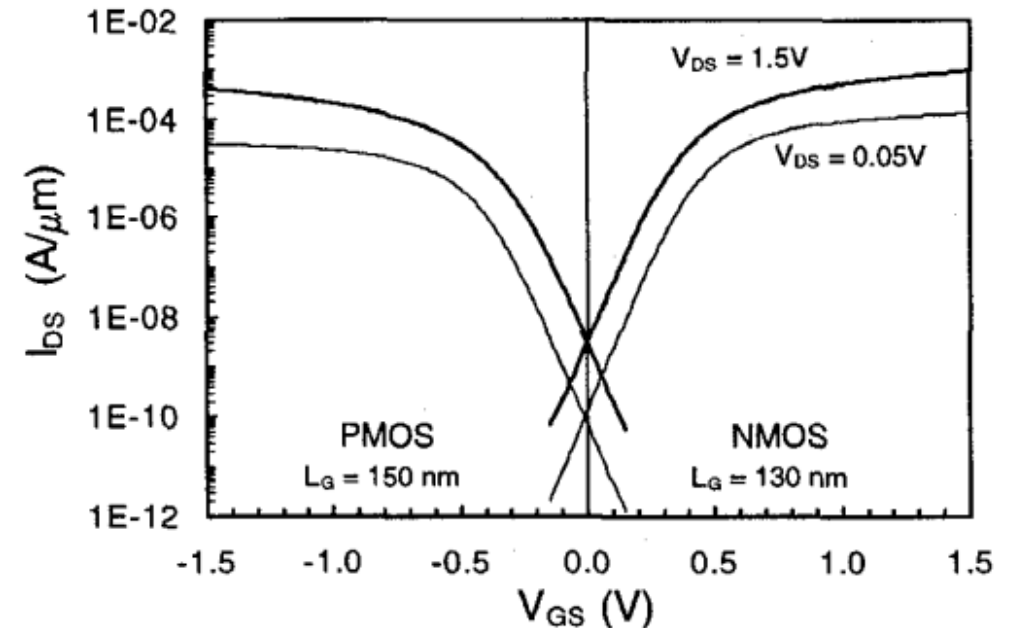
- 130nm: 2000 (Intel, IEDM)
- 90nm: 2003 (Intel, IEDM)
- 65nm: 2004 (Intel, IEDM)
- 45nm: 2007 (Intel, IEDM)
- 32nm: 2008 (Intel, IEDM)
- 22nm: 2012 (Intel, VLSI)

For your interest, watch the video,
[Eng][VLSIDevices2025] L23, from 33:53.

- ➔ – 16nm: 2013 (TSMC, IEDM), 14nm: 2014 (Intel, IEDM)
- 10nm: 2016 (TSMC, IEDM)
- 7nm: 2016 (TSMC, IEDM)
- 5nm: 2019 (TSMC, IEDM)
- 3nm: 2022 (TSMC, IEDM)
- 2nm: 2024 (TSMC, IEDM)

Homework#2

- Due: 08:00 on Sep. 8
- Submit your report through GIST LMS system.
- 1) Download Intel's IEDM 1998 abstract for 0.18 μm technology.
 - See Fig. 6.
 - Calculate the DIBL for both devices.
- 2) For 0.25 μm devices,
 - Estimate C (of course, per width) for N/PMOSFETs.
 - Compare it with $\epsilon_{ox} \frac{L}{t_{ox}}$.



Thank you!